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PATENT  
Attorney Docket No.: 014089-002580US

On

*August 29, 2005*

TOWNSEND and TOWNSEND and CREW LLP

By:

*Il Suena*

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re application of:

VEERASAMY, VIJAYEN, et al.

Application No.: 10/773,796

Filed: February 6, 2004

For: RECORDING MEDIA HAVING  
PROTECTIVE OVERCOATS OF  
HIGHLY TETRAHEDRAL  
AMORPHOUS CARBON AND  
METHODS FOR THEIR PRODUCTION

Examiner: PADGETT, Marianne L.

Art Unit: 1762

SUPPLEMENTAL INFORMATION  
DISCLOSURE STATEMENT UNDER 37  
CFR §1.97 and §1.98

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Sir:

The references cited on attached form PTO/SB/08A&B are being called to the attention of the Examiner. Copies of the references [in compliance with the requirements of 1287 OG 163] are enclosed.

It is respectfully requested that the cited references be expressly considered during the prosecution of this application, and the references be made of record therein and appear among the "references cited" on any patent to issue therefrom.

09/01/2005 CNGUYEN2 00000018 201430 10773796

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As provided for by 37 CFR 1.97(g) and (h), no inference should be made that the information and references cited are prior art merely because they are in this statement and no representation is being made that a search has been conducted or that this statement encompasses all the possible relevant information.

This IDS is being filed before the mailing date of the final Office Action or Notice of Allowance.

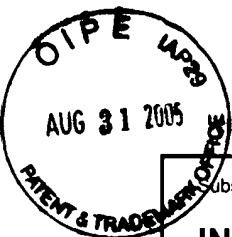
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Respectfully submitted,



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<b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b>  (use as many sheets as necessary)			<b>Complete if Known</b>		
			Application Number	10/773,796	
			Filing Date	February 6, 2004	
			First Named Inventor	Veerasamy, Vijayen	
			Art Unit	1762	
			Examiner Name	PADGETT, Marianne L.	
Sheet	1	of	2	Attorney Docket Number	014089-002580US

U.S. PATENT DOCUMENTS+					
Examiner Initials*	Cite No. <sup>1</sup>	Document Number	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number Kind Code <sup>2</sup> (if known)			

FOREIGN PATENT DOCUMENTS								
Examiner Initials*	Cite No. <sup>1</sup>	Foreign Patent Document			Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T <sup>6</sup>
		Country Code <sup>3</sup>	Number <sup>4</sup>	Kind Code <sup>5</sup> (if known)				
	0001	EP	0 552 491	A1	07-28-1993	Collins et al.		<input type="checkbox"/>
	0002	EP	0 595 564	A2	05-04-1994	Takai et al.		<input type="checkbox"/>
	0003	EP	0 700 033	A2	03-06-1996	Gray		<input type="checkbox"/>
	0004	JP	2-168540	A	06-28-1990	Oda		<input type="checkbox"/>
	0005	JP	5-143971	A	06-11-1993	Okumura et al.		<input type="checkbox"/>
	0006	JP	6-139560	A	05-20-1994	Miyazaki		<input type="checkbox"/>
	0007	JP	6-349054	A	12-22-1994	Onodera		<input type="checkbox"/>

NON PATENT LITERATURE DOCUMENTS			
Examiner Initials *	Cite No. <sup>1</sup>	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T <sup>2</sup>
	0008	Aisenberg, S. et al.; "Ion-Beam Deposition of Thin Films of Diamondlike Carbon," <u>J. Appl. Phys.</u> ; June 1971; pp. 2953-2958; vol. 42; No. 7.	
	0009	Boxman, R.L. et al.; "Recent Progress in Filtered Vacuum Arc Deposition;" <u>Paper submitted, Int. Conf. Metallurgical Coatings and Thin Films</u> ; April 1996; San Diego.	
	0010	Chhowalla, M. et al.; "Deposition of Smooth Tetrahedral Amorphous Carbon Thin Films Using a Cathodic Arc Without a Macroparticle Filter;" <u>Appl. Phys. Lett.</u> ; 1995; pp. 894-896; vol. 67; No. 7.	
	0011	Chhowalla, M. et al.; "Stationary Carbon Cathodic Arc: Plasma and Film Characterization;" <u>J. Appl. Phys.</u> ; 1996; pp. 2237-2244; vol. 79; No. 5.	
	0012	Dissertation by Dieter Martin, 1995.	
	0013	Dissertation by Manfred Weiler, 1994.	
	0014	Dissertation by Vijayen S. Veerasamy, 1994.	
	0015	Grill, A. et al.; "Diamondlike Carbon Deposited by DC PACVD;" <u>Diamond Films and Techn.</u> ; 1992; pp. 219-233; vol. 1, No. 4.	

Examiner Signature		Date Considered	
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\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

<sup>1</sup> Applicant's unique citation designation number (optional). <sup>2</sup> Applicant is to place a check mark here if English language Translation is attached.

Substitute for form 1449A&B/PTO				<b>Complete if Known</b>	
<b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b>  (use as many sheets as necessary)				Application Number	10/773,796
				Filing Date	February 6, 2004
				First Named Inventor	Veerasamy, Vijayan
				Art Unit	1762
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Sheet	2	of	2	Attorney Docket Number	014089-002580US

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Examiner Initials *	Cite No. <sup>1</sup>	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T <sup>2</sup>
	0016	Grill, A., et al.; "Diamondlike Carbon Films by rf Plasma-Assisted Chemical Vapor Deposition from Acetylene," <u>IMB J. Res. Develop.</u> ; November 1990; pp.849-857; vol. 34; No. 6.	
	0017	Kuhn, M. et al.; "Deposition of Carbon Films By A Filtered Cathodic Arc;" <u>Diamond and Related Materials</u> ; August 1993; pp.1350-1354; vol. 2; No. 10.	
	0018	Oechsner, H. et al.; "An RF Plasma Beam Source for Thin Film and Surface Technology;" <u>Proc. 1st Int. Conf. on Plasma Surface Engineering</u> , Garmisch Partenkirchen, 1988; 1989; pp. 1017-1024; vol. 11; DGM Informationen Gesellschaft, Obvuroel.	
	0019	Oechsner, H.; "Electron Cyclotron Wave Resonances and Power Absorption Effects in Electrodeless Low Pressure H.F. Plasmas with a Superimposed Static Magnetic Field;" <u>Plasma Physics</u> ; 1974; pp. 835-844; vol. 16.	
	0020	Park, K.C. et al.; "Enhancement of Field-Emission Characteristics by Using Hydrogen-Free Diamond-Like Carbon Film Deposited by Plasma-Enhanced Chemical Vapor Deposition;" <u>SID 96 Digest</u> ; 1996; pp. 49-52.	
	0021	Pfeiffer, B.; "Skin Effect in Anisotropic Plasmas and Resonance Excitation of Electron-Cyclotron Waves. I. Theory;" <u>Journal of Applied Physics</u> ; 1966; pp. 1624-1627; vol. 37; No. 4.	
	0022	PR Newswire. CeBIT Showcase for Major Advance in Magnetic Disk Storage Capacity; Feb. 2000; Hanover, Germany; website: <a href="http://www.prnewswire.com">http://www.prnewswire.com</a> ; (Feb. 19, 2000).	
	0023	Sager, O.; "The Influence of Nonuniform Density Distribution and Electron Temperature on the Helicon-Resonances in Low Pressure Discharges;" 1971.	
	0024	Szuszczewicz, Edward P.; "Spatial Distributions of Plasma Density in a High-Frequency Discharge with a Superimposed Static Magnetic Field;" <u>The Physics of Fluids</u> ; 1972; pp. 2240-2246; vol. 15; No. 12.	
	0025	Thesis by Armin Fuchs, 1987.	
	0026	Thesis by Franz Schon, 1968.	
	0027	Thesis by Manfred Weiler, 1989.	
	0028	Veerasamy, V.S. et al.; "Electronic Density of States in Highly Tetrahedral Amorphous Carbon;" <u>Solid-State Electronics</u> ; 1994; pp. 319-326; vol. 37; No. 2.	
	0029	Weiler, M. et al.; "Highly Tetrahedral, Diamond-like Amorphous Hydrogenated Carbon Prepared from a Plasma Beam Source;" <u>Appl. Phys. Lett.</u> ; 1994; pp. 2797-2799; vol. 64; No. 23.	
	0030	Weiler, M. et al.; "Preparation and Properties of Highly Tetrahedral Hydrogenated Amorphous Carbon;" <u>Physical Review B</u> ; 1996; pp. 1594-1608; vol. 53; No. 3.	
	0031	Weiler, M. et al.; "Structure of Amorphous Hydrogenated Carbon: Experiment and Computer Simulation;" <u>Diamond and Related Materials</u> ; 1994; pp. 245-253; vol. 3.	

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